

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				Docket Number (Optional) 16791 (03006)		Application Number Unassigned	
				Applicant(s) Alistair C.H. Rowe, et al.			
				Filing Date Herewith		Group Art Unit Unassigned	

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
DS		C.A. Mead, et al.; "Fermi Level Position at Metal-Semiconductor Interfaces"; <u>Physical Review</u> ; Vol. 134; No. 3A; pp. A713-16; (1964)
DS		G. Margaritondo; "Interface states at semiconductor junctions"; <u>Rep. Prog. Phys.</u> ; Vol. 62; pp. 7650-808; (1999)
DS		C.S. Gworek, et al.; "Pressure dependence of Cu, Ag, and Fe/n-GaAs Schottky barrier heights"; <u>Phy. Rev.B</u> ; Vol. 64; pp. 045322-1 - 6; (2001)
DS		Peter Van Vessel et al.; "Rediscovering the Strain Gauge Pressure Sensor"; <u>Sensors</u> ; 8 pps.; (1999)

EXAMINER <i>Octavia Davis</i>	DATE CONSIDERED 10/21/04
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DS		Adhesives List printed from <u>www.tokynosokki.co.jp/e/product</u> . . . ; on 6/27/2003
DS		Fujidura Semiconductor Pressure Sensors printed from <u>www.fujidura.co.jp/sensor/press/intro</u> . . ." on 6/27/2003
DS		Y. Ohmura; "Piezoresistance Effect in p-Type Semiconductors Si and Ge"; 21 st International Conference on The Physics of Semiconductors; Vol. 1; pp. 273-76; (1992

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